

WHAT IS CLAIMED IS:

1. A substrate processing apparatus comprising:
 - at least one transfer mechanism configured to transfer a substrate and at least one processing mechanism configured to process the substrate;
 - an earthquake detector configured to detect an earthquake; and
 - a controller configured to control the at least one transfer mechanism and the at least one processing mechanism according to a detection result of the earthquake detector,wherein, in response to receiving a detection signal of a P wave (initial tremor wave) and an S wave (principal fluctuation wave) from the earthquake detector, the controller is configured to be capable of performing a stopping operation of the at least one transfer mechanism according to a stopping method that has been pre-selected for the detection signal, and
 - wherein, if not stopping has been pre-selected as the stopping method, the controller is capable of controlling a substrate process to continue.
2. The substrate processing apparatus of Claim 1, wherein the stopping operation of the at least one transfer mechanism is configured to be individually set with respect to the P wave and the S wave.
3. The substrate processing apparatus of Claim 1, wherein the stopping method is one of deceleration stop, immediate stop, step stop, cycle stop, and not stopping.
4. The substrate processing apparatus of Claim 1, wherein the at least one transfer mechanism includes a plurality of transfer mechanisms, and
 - wherein the stopping operation is configured to be capable of being selected with respect to each of transfer mechanisms according to the detection result from the earthquake detector.

5. The substrate processing apparatus of Claim 1, wherein the at least one transfer mechanism is at least one selected from the group of a pod conveyor, a substrate conveyor, a boat elevator, and a rotator.
6. The substrate processing apparatus of Claim 5, wherein when a stopping operation of the boat elevator of the at least one transfer mechanism is set to cycle stop, the boat elevator is configured to be capable of returning a boat to an initial position regardless of whether the boat is being raised or being lowered.
7. The substrate processing apparatus of Claim 5, wherein when a stopping operation of the boat elevator of the at least one transfer mechanism is not set, the controller is configured to be capable of performing a substrate processing process including a loading step, a processing step, and an unloading step even when the earthquake is detected while a boat is being raised.
8. The substrate processing apparatus of Claim 1, wherein the at least one transfer mechanism is configured to be capable of setting presence or absence of the stopping operation.
9. The substrate processing apparatus of Claim 1, wherein when the P wave is detected, the controller is configured to be capable of maintaining an earthquake detection alarm even when the S wave is not detected.
10. The substrate processing apparatus of Claim 1, wherein the controller is configured to be capable of selecting the stopping operation of the at least one transfer mechanism according to an earthquake intensity.
11. The substrate processing apparatus of Claim 1, wherein the at least one processing

mechanism includes a plurality of processing mechanisms, and

wherein a stopping operation is configured to be capable of being set with respect to each of the processing mechanisms.

12. The substrate processing apparatus of Claim 1, wherein the controller is configured to be capable of selecting an operation of the at least one processing mechanism according to the P wave and the S wave.

13. The substrate processing apparatus of Claim 1, wherein the at least one processing mechanism includes a plurality of processing mechanisms, and
wherein a stopping operation is configured to be capable of being selected with respect to each of the processing mechanisms according to the detection result from the earthquake detector.

14. The substrate processing apparatus of Claim 1, wherein the controller is configured to be capable of selecting a stopping operation of the at least one processing mechanism according to an earthquake intensity.

15. A method of manufacturing a semiconductor device, comprising:
a substrate transferring process of operating at least one transfer mechanism configured to transfer a substrate;
a substrate processing process of operating at least one processing mechanism configured to process the substrate;
receiving a detection signal of at least one selected from the group of a P wave (initial tremor wave) and an S wave (principal fluctuation wave) of an earthquake detected during execution of the substrate transferring process or the substrate processing process; and
performing a stopping operation of the at least one transfer mechanism according to a

stopping method that has been pre-selected for the received detection signal of the at least one selected from the group of the P wave and the S wave,

wherein, in the act of performing the stopping operation, if not stopping has been pre-selected as the stopping method, the substrate continues to be processed.

16. A program that causes a controller to perform a process, wherein the program is executed in a substrate processing apparatus including at least one transfer mechanism configured to transfer a substrate, at least one processing mechanism configured to process the substrate, an earthquake detector configured to detect an earthquake, and the controller configured to control the at least one transfer mechanism and the at least one processing mechanism according to a detection result of the earthquake detector, the controller being configured to be capable of performing a stopping operation of the at least one transfer mechanism according to a P wave (initial tremor wave) and an S wave (principal fluctuation wave), the process comprising:

receiving a detection signal of at least one selected from the group of the P wave and the S wave of the earthquake; and

performing the stopping operation of the at least one transfer mechanism according to a stopping method that has been pre-selected for the received detection signal of the at least one selected from the group of the P wave and the S wave,

wherein, in the act of performing the stopping operation, if not stopping has been pre-selected as the stopping method, the controller is capable of controlling a substrate process to continue.